



[10191/1629]

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Inventor(s) : LAERMER et al. Confirmation No.: 5642
Serial No. : 09/720,761
Filed : March 26, 2001
For : METHOD OF PLASMA ETCHING OF SILICON
Examiner : K. Chen
Art Unit : 1765
Customer No. : 26646

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Atty's Signature DERVIS MAGISTRE
KENYON & KENYON LLP

AMENDMENT

SIR:

In response to the Office Action dated February 22, 2006, please amend the above-identified application as set forth below.

Amendments to the Specification do not appear in this paper.

Amendments to the Claims are reflected in the listing of the claims which begins on page 2 of this paper.

Amendments to the Drawings do not appear in this paper

Remarks begin on page 6 of this paper.